



Docket No.: 060188-0702

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of	:	Customer Number: 20277
	:	
Akio MISAKA	:	Confirmation Number: 8679
	:	
Application No.: 10/717,598	:	Group Art Unit: 1756
	:	
Filed: November 21, 2003	:	Examiner: ROSASCO, STEPHEN D
	:	

For: PHOTOMASK, PATTERN FORMATION METHOD USING PHOTOMASK AND MASK
DATA CREATION METHOD

AMENDMENT

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In response to the Office Action dated December 19, 2005, having a three-month shortened statutory period for response set to expire March 19, 2006, a petition for a one-month extension of time up to and including April 19, 2006, being filed concurrently herewith, please amend the above-identified application as follows.